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IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicants:

Robert H. Blick, et al.

Title:

ENHANCEMENT OF

FABRICATION YIELDS OF NANOMECHANICAL DEVICES BY THIN FILM DEPOSITION

Appl. No.:

10/802,259

Filing Date:

03/17/2004

Examiner:

Mai Huong C. Tran

Art Unit:

2818

CERTIFICATE OF MAILING I hereby certify that this correspondence is being deposited with the United States Postal Service with sufficient postage as First Class Mail in an envelope addressed to: Commissioner for Patents, P.O. Box 1450, Alexandria, VA 22313-1450, on the date below. Harry C. Engstrom (Printed Name) July 12, 2005 (Date of Deposit)

RESPONSE TO RESTRICTION REQUIREMENT

Commissioner for Patents P.O. Box 1450 Alexandria, VA 22313-1450

Sir:

In response to the Office Action of June 22, 2005, imposing a restriction requirement on the above-referenced application, Applicants provisionally elected the claims of Group II, Claims 1-20 and 26-44, for initial examination, and request reconsideration and withdrawal of the restriction requirement for reasons discussed below.

Applicants believe no fee is due for this filing. However, should any fee be required, the Commissioner is hereby authorized to charge such fee in connection with this submission to Deposit Account No. 50-2350. A duplicate copy of this Response is enclosed for such purposes.

REMARKS

The Office Action of June 22, 2005 imposed a restriction requirement between Claims 21-25 (Group I), drawn to a semiconductor device, and Claims 1-20 and 26-44 (Group II), drawn to a process of making a semiconductor device. Applicants have provisionally elected Claims 1-20 and 26-44.